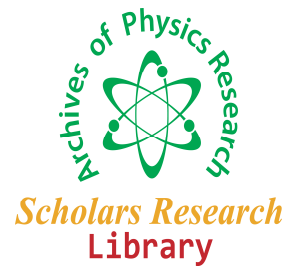




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Steady-State and Transient Electron Transport within bulk $\text{InAs}_x\text{P}_{1-x}$, InAs and InP using A Semi-classical Three-Valley Monte Carlo Simulation Analysis

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Abstract

We study how electrons, initially in thermal equilibrium, drift under the action of an applied electric field within bulk zincblende $\text{InAs}_x\text{P}_{1-x}$, InAs and InP. Calculations are made using a non-parabolic effective mass energy band model, Monte Carlo simulation that includes all of the major scattering mechanisms. The band parameters used in the simulation are extracted from optimized pseudopotential band calculations to ensure excellent agreement with experimental information and ab-initio band models. The effects of alloy scattering on the electron transport physics are examined. For all materials, it is found that electron velocity overshoot only occurs when the electric field is increased to a value above a certain critical field, unique to each material. This critical field is strongly dependent on the material parameters. Transient velocity overshoot has also been simulated, with the sudden application of fields up to 1600 kV m^{-1} , appropriate to the gate-drain fields expected within an operational field effect transistor. The electron drift velocity relaxes to the saturation value of about $1.5 \times 10^5 \text{ ms}^{-1}$ within 4 ps, for all crystal structures. The steady-state and transient velocity overshoot characteristics are in fair agreement with other recent calculations.

Key words: Non-parabolic; pseudopotential; alloy scattering; velocity overshoot; critical field.

Introduction

InP and InAs offer the prospect of mobilities comparable to GaAs and are increasingly being developed for the construction of optical switches and optoelectronic devices. While GaAs has been extensively studied [1-3], InAs and InP and alloy constructed from them like $\text{InAs}_x\text{P}_{1-x}$, have yet to be examined to the same extent. Alloys of InAs and InP have unfortunately proved to be a difficult material to work with in practice and very little experimental work on $\text{InAs}_x\text{P}_{1-x}$ material and devices have been done because of technical problems in forming Schottky contacts with sufficiently high barrier potentials. Nevertheless some experimental work has been done on

other types of InAs and InP field-effect transistor, most notably MISFETs [4-5], and there is every reason to be optimistic that some form of heterojunction under the gate may well overcome the problem of the low barrier.

Improved electron transport properties are one of the main targets in the ongoing study of binary and ternary InP, InAs and $\text{InAs}_x\text{P}_{1-x}$ materials. The Monte Carlo technique has proved valuable for studying non-equilibrium carrier transport in a range of semiconductor materials and devices [6-7]. However, carrier transport modeling of InP and InAs materials has only recently begun to receive sustained attention, now that the growth of compounds and alloys is able to produce valuable material for the electronics industry. In this communication we present Monte Carlo calculations of steady-state and transient electron transport conditions in InP, InAs and $\text{InAs}_x\text{P}_{1-x}$. We demonstrate the effect of injection energy and electric field on the transient electron transport. The differences in transport properties are analyzed in terms of important material parameters.

Our current approach employs a one-dimensional ensemble Monte Carlo technique to investigate steady-state and transient electron transport in InP, InAs and $\text{InAs}_x\text{P}_{1-x}$. However, the momentum space treatment is three dimensional, and the scattering events consider all three dimensions. Specifically, our model includes the three lowest valleys of the conduction band with non-parabolicity. This article is organized as follows.

Details of the conduction band parameters and the Monte Carlo simulation are presented in section 2, and the results of steady-state and transient transport simulations are discussed in section 3.

Model details

Our ensemble Monte Carlo simulations of electron transport in zincblende InP, InAs and $\text{InAs}_x\text{P}_{1-x}$ are similar to those of Arabshahi *et al* [8-9]. As indicated earlier, a three-valley model for the conduction band is employed.

In order to calculate the electron drift velocity for large electric fields, consideration of conduction band satellite valleys is necessary. The first-principles band structure of zincblende InAs, InP and $\text{InAs}_x\text{P}_{1-x}$ predicts a direct band gap located at the Γ point and lowest energy conduction band satellite valleys at the X point and at the L point. In our Monte Carlo simulation, the Γ valley, the three equivalent X valleys, the four equivalent L valleys, are represented by ellipsoidal, nonparabolic dispersion relationships of the following form [10-12]

$$E(k)[1 + \alpha_i E(k)] = \frac{\hbar^2 k^2}{2m^*} \quad (1)$$

where m^* is effective mass at the band edge and α_i is the non-parabolicity coefficient of the i -th valley given by Kane model [13] as

$$\alpha_i = \frac{1}{E_g} \left[1 - \frac{2m^*}{m_0} \right] \left[1 - \frac{E_g \Delta}{3(E_g + \Delta)(E_g + 2\Delta/3)} \right] \quad (2)$$

where E_g is the band-gap energy and Δ is the spin-orbit splitting.

We assume that all donors are ionized and that the free-electron concentration is equal to the

dopant concentration. For each simulation, the motion of ten thousand electron particles are examined, the temperature being set to 300 K, and the doping concentration being set to 10^{17}cm^{-3} . In the case of the ellipsoidal, non-parabolic conduction valley model, the usual Herring-Vogt transformation matrices are used to map carrier momenta into spherical valleys when particles are drifted or scattered. Electrons in bulk material suffer intravalley scattering by polar optical, non-polar optical and acoustic phonons scattering, intervalley phonons, and ionised impurity scattering.

Acoustic scattering is assumed elastic and the absorption and emission rates are combined under the equipartition approximation, which is valid for lattice temperatures above 77 K. Elastic ionised impurity scattering is described using the screened Coulomb potential of the Brooks-Herring model. Band edge energies, effective masses and non-parabolicities are derived from empirical pseudopotential calculations. Important parameters used throughout the simulations are listed in tables 1-2.

	InAs	InP	InAs _{0.2} P _{0.8}	InAs _{0.8} P _{0.2}
m_{Γ}	5667	4810	4981	5495
m_L	4280	5300	5096	4484
m_x	14.6	12.4	12.84	14.16
α_{Γ}	12.25	9.55	10.09	11.71
α_L	4.9	8.3	7.62	5.58
Γ -X	0.015	0.06	0.05	0.024
Γ -L	1	1	1	1

Table 1: Valley parameter selections for InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} [3-5]

	InAs	InP	InAs _{0.2} P _{0.8}	InAs _{0.8} P _{0.2}
Density ρ (kgm^{-3})	5667	4810	4981	5495
Longitudinal sound velocity v_s (ms^{-1})	4280	5300	5096	4484
Low-frequency dielectric constant ϵ_s	14.6	12.4	12.84	14.16
High-frequency dielectric constant ϵ_{∞}	12.25	9.55	10.09	11.71
Acoustic deformation potential D(eV)	4.9	8.3	7.62	5.58
Polar optical phonon energy (eV)	0.015	0.06	0.05	0.024
Intervalley deformation potential (eVm^{-1})	1	1	1	1
Intervalley phonon energies (meV)	11.2	29	25.44	14.76

Table 2: Material parameter selections for InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} [3-5]

Results

Figure 1 shows the simulated velocity-field characteristics of zincblende InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} semiconductors at 300 K, with a background doping concentration of 10^{17} cm^{-3} , and with the electric field applied along one of the cubic axes. The simulations suggest that the peak drift velocity for zincblende InAs is $3.4 \times 10^5 \text{ ms}^{-1}$, while that for InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} are about $\sim 2.3 \times 10^5 \text{ ms}^{-1}$, $2.5 \times 10^5 \text{ ms}^{-1}$ and $3.2 \times 10^5 \text{ ms}^{-1}$, respectively. At higher electric fields, intervalley optical phonon emission dominates, causing the drift velocity to saturate at around $1.5 \times 10^5 \text{ ms}^{-1}$ for all materials.

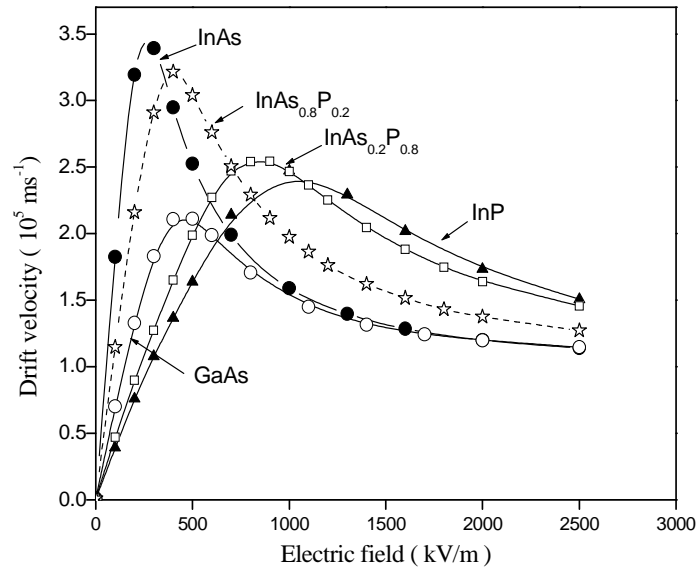


Figure 1: Calculated steady-state electron drift velocity in bulk zincblende InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} using non-parabolic band models at room temperature

The calculated drift velocities apparent from figure 1 are fractionally lower than those that have been calculated by Adachi *et al.* [14-16], who assumed an effective mass in the upper valleys equal to the free electron mass. The threshold field for the onset of significant scattering into satellite conduction band valleys is a function of the intervalley separation and the density of electronic states in the satellite valleys.

The valley occupancies for the Γ , X and L valleys are illustrated in figure 2 and show that the inclusion of the satellite valleys in the simulation is important. Significant intervalley scattering into the satellite valleys occurs for fields above the threshold field for each material. This is important because electrons which are near a valley minimum have small kinetic energies and are therefore strongly scattered. It is apparent that intervalley transfer is substantially larger in InAs over the range of applied electric fields shown, due to the combined effect of a lower Γ effective mass, lower satellite valley separation energy, and slightly lower phonon scattering rate within the Γ valley.

We have also examined transient electron transport in bulk InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} semiconductors. The transient response of electrons in these materials are compared in figure 3 for fields up to 1600 kV m^{-1} strengths. In InAs, we find very little or no overshoot occurs below the threshold field of 400 kV m^{-1} . As the electric field strength is increased to a value above the threshold field, overshoot begins to occur. As the field strength is increased further, both the peak

overshoot velocity increases and the time for overshoot relaxation decreases.

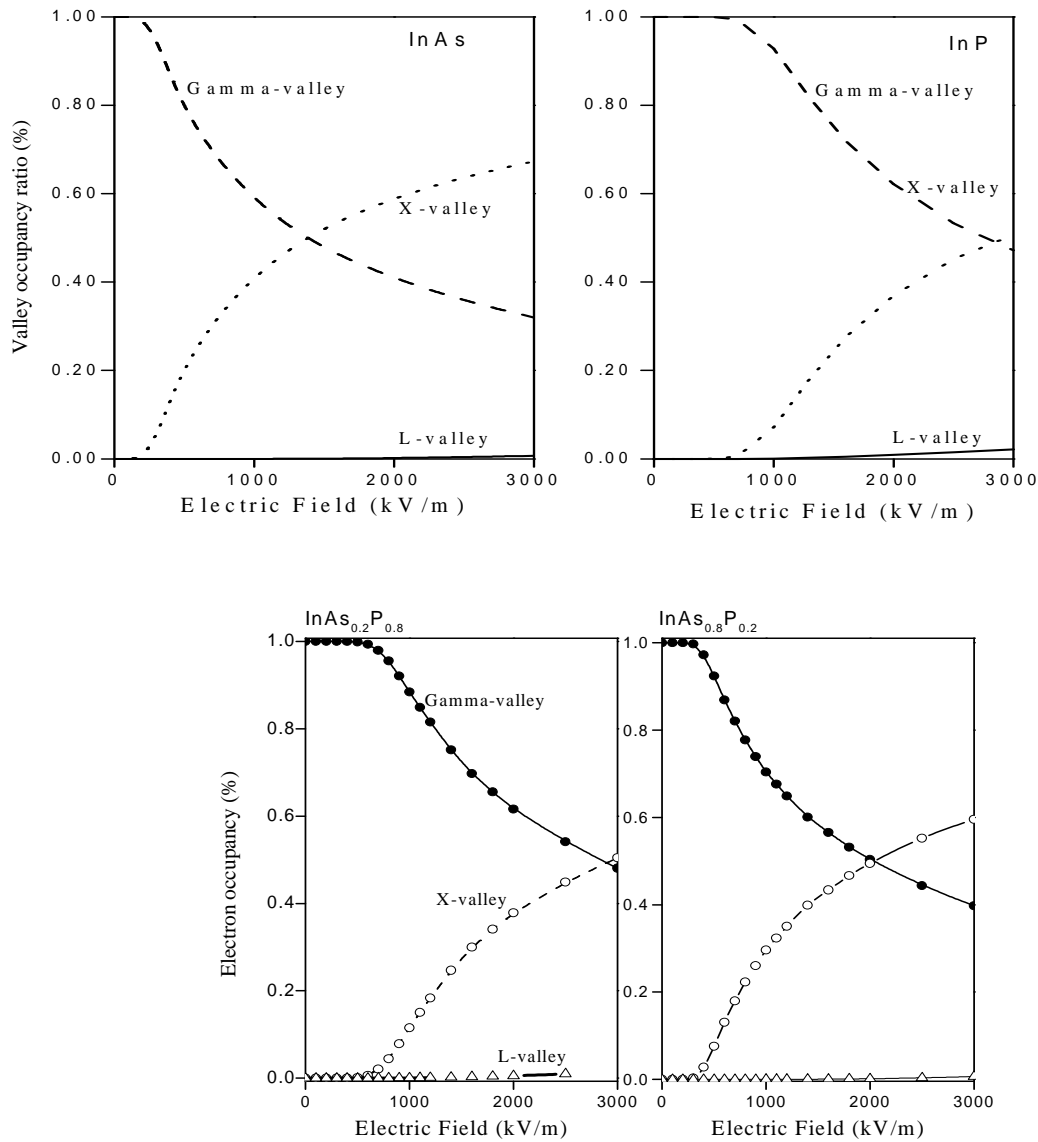


Figure 2: Fractional occupation of the central Γ and satellite valleys of zincblende InAs, InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ as a function of applied electric field using the non-parabolic band model at room temperature

In InAs, the velocity overshoot initially increases more rapidly with increasing electric field due to the lower Γ valley effective mass. For example, at 1600 kV m^{-1} , the maximum overshoot velocity for InAs is about $8 \times 10^5 \text{ ms}^{-1}$, whereas for InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ it is about $4 \times 10^5 \text{ ms}^{-1}$, $5 \times 10^5 \text{ ms}^{-1}$ and $7 \times 10^5 \text{ ms}^{-1}$, respectively. It is found also that for the same value of the electric field above the threshold value, the electron drift velocity is always smaller in InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ than in InAs.

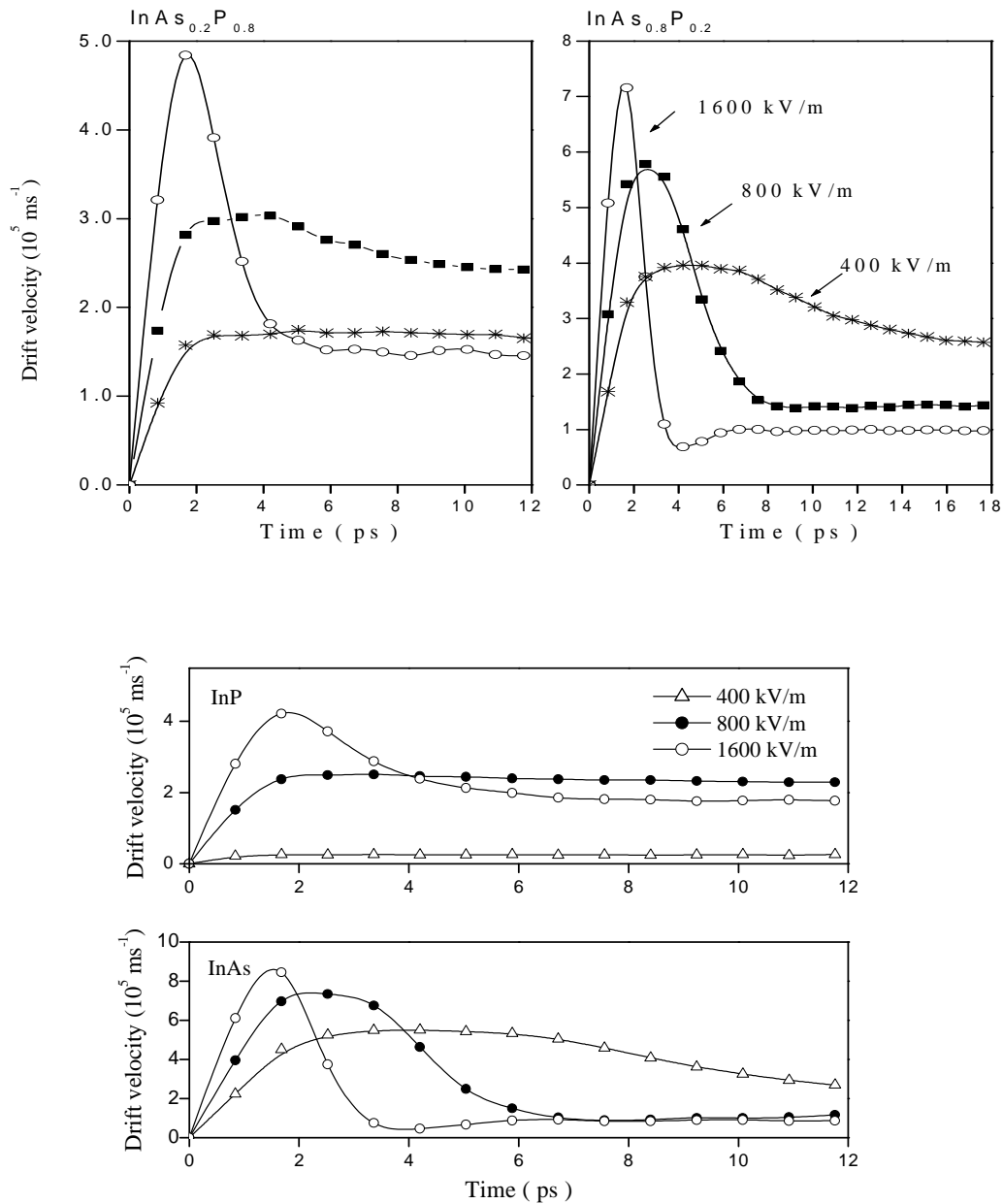


Figure 3: A comparison of the velocity overshoot effect exhibited by InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} semiconductors as calculated by our Monte Carlo simulation. The donor concentration is 10¹⁷ cm⁻³ and the temperature is 300 K

Figure 4 shows average velocity of electrons in InAs, InP, InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} as a function of distance. We note that for the applied field selections 400 to 1600 kV/m the average electron velocity reaches steady-state very quickly, with little or no velocity overshoot. In contrast, for applied electric field selections above 400 kV/m, significant velocity overshoot occurs. It is suggested that in InAs_{0.2}P_{0.8} and InAs_{0.8}P_{0.2} 400 kV/m is a critical field for the onset of velocity

overshoot. As mentioned above, 400 kV m^{-1} also corresponds to the peak in the velocity-field characteristic associated with $\text{InAs}_{0.2}\text{P}_{0.8}$. Steady-state Monte Carlo simulations suggest that this is the point at which significant upper valley occupation begins to occur, as shown in figure 2. This suggests that velocity overshoot is related to the transfer of electrons to the upper valleys. To optimize device performance, we have to minimize the transit time over a given distance.

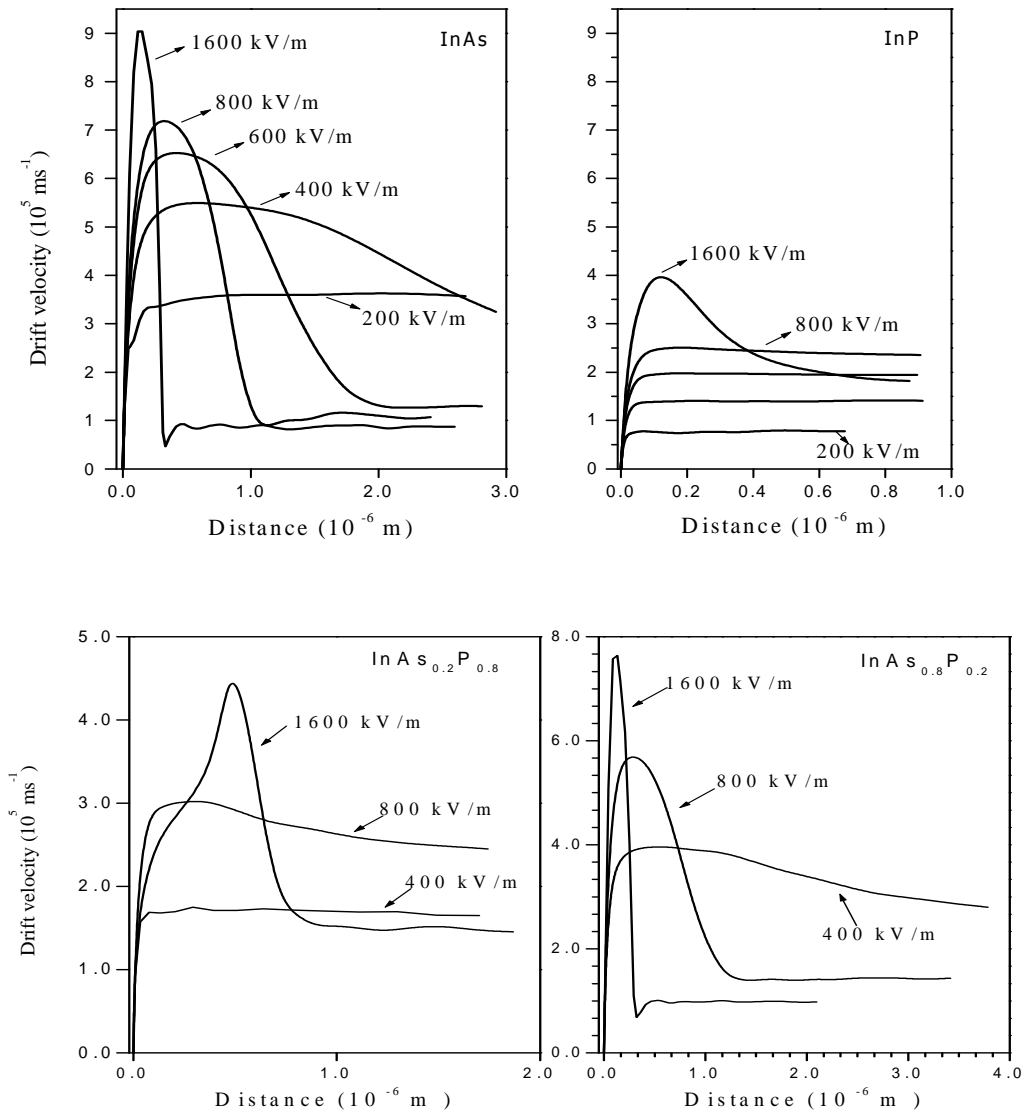


Figure 4: A comparison of the average electron velocity as a function of the displacement for various applied fields in, InAs, InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ semiconductors. In all cases, we have assumed an initial zero field distribution, a crystal temperature of 300 K and a doping concentration of 10^{17} cm^{-3} .

From figure 5, it can be seen that there is tradeoff between the peak overshoot velocity and the distance taken to achieve steady-state. In particular, when the applied electric field is set to 1600 kV m^{-1} the peak overshoot velocity of $\text{InAs}_{0.8}\text{P}_{0.2}$ is $7.8 \times 10^5 \text{ ms}^{-1}$, while the corresponding steady-

state drift velocity, $1.5 \times 10^5 \text{ ms}^{-1}$, is achieved after just $0.2 \text{ }\mu\text{m}$.

However, for an applied field of 400 kVm^{-1} , just above the critical field, the peak overshoot velocity is only $4 \times 10^5 \text{ ms}^{-1}$, and it takes longer, about $0.8 \text{ }\mu\text{m}$, to achieve the corresponding steady-state drift velocity, $3 \times 10^5 \text{ ms}^{-1}$. Similar results are noted for $\text{InAs}_{0.2}\text{P}_{0.8}$, as is seen in figure 5. In particular, the critical field denoting the onset of velocity overshoot coincides, almost exactly, with the field at which the peak drift velocity in the steady-state velocity field characteristic is found, i.e., 200 kVm^{-1} for InAs and 800 kVm^{-1} for InP. The correspondence between the critical field at which the onset of velocity overshoot effects occur and the peak in the steady-state velocity field characteristic appears to be valid for the case of other III-V semiconductors as well.

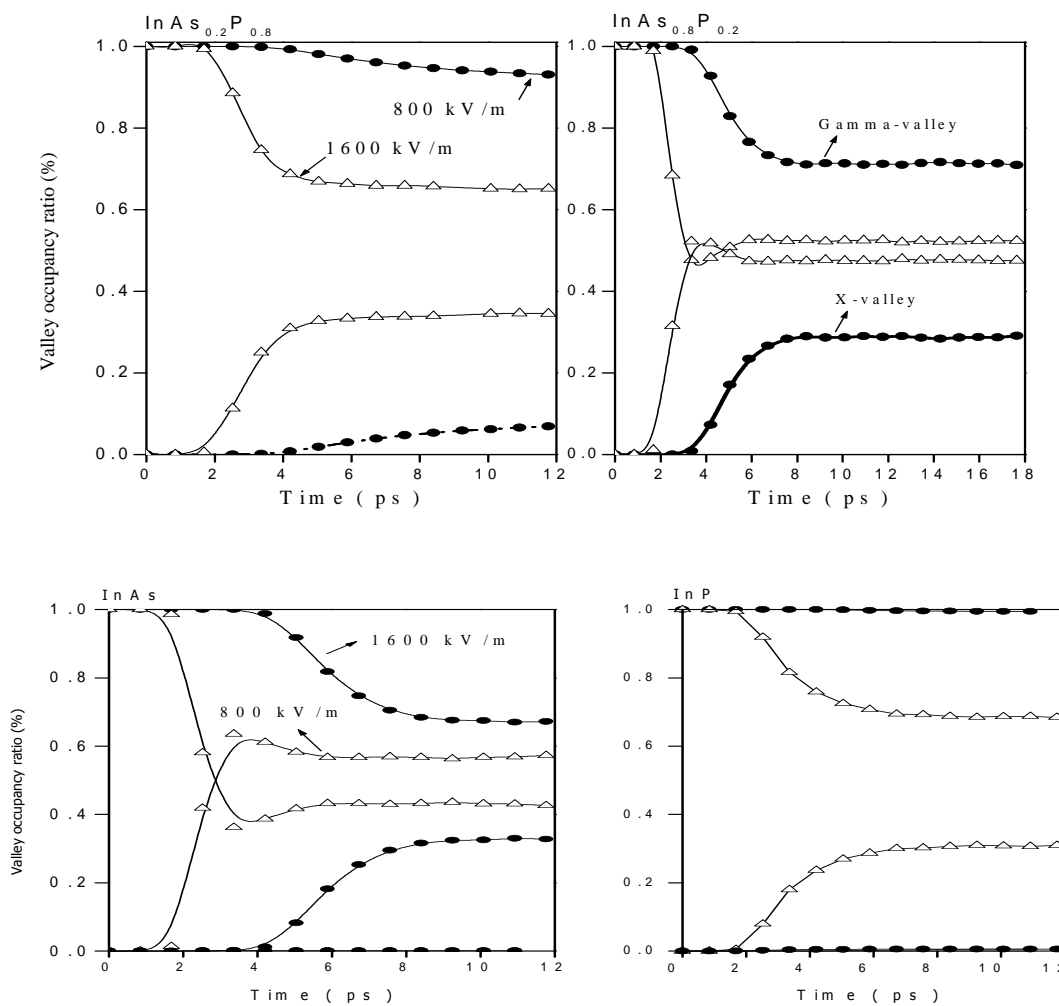


Figure 5: Comparison of the valley occupancies as a function of applied electric field in InAs, InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ for Γ , X and L valleys at room temperature

Electron transport at 300 K in bulk zincblende InAs, InP, $\text{InAs}_{0.2}\text{P}_{0.8}$ and $\text{InAs}_{0.8}\text{P}_{0.2}$ have been simulated using an ensemble Monte Carlo simulation. Using valley models to describe the

electronic bandstructure, calculated velocity-field characteristics are in fair agreement with other calculations. Saturation drift velocities $\sim 1.5 \times 10^5 \text{ ms}^{-1}$ match recent measurements on low-doped bulk samples. The velocity-field characteristics of the materials show similar trends, reflecting the fact that all the semiconductors have satellite valley effective densities of states several times greater than the central Γ valley. However, the peak velocity in $\text{InAs}_{0.2}\text{P}_{0.8}$ occurs at a field $\sim 700 \text{ kVm}^{-1}$, 2 times larger than for $\text{InAs}_{0.8}\text{P}_{0.2}$. This is a consequence of the large Γ valley effective mass in $\text{InAs}_{0.2}\text{P}_{0.8}$ structure. This reduced valley effective mass in $\text{InAs}_{0.8}\text{P}_{0.2}$ permits substantial population of the upper valleys and velocity saturation at far lower electron temperatures than in InP.

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